Institute of Radiation Physics Radiation Source ELBE

Status report of GaN photocathode 3rd collaboration BETH Meeting, online, 1st March 2021

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Agenda



- Short overview of GaN chamber (Set-up)
- Thermal heat treatment
- Main caesium activation
- Highlights 2020
- Latest activations on GaN on sapphire
- GaN on copper (Siegen)
- Summary and Outlook



GaN chamber





thermal heat treatment

Sample is usual chemical cleaned with EtOH, Piranha solution (H_2O_2 , H_2SO_4), HCL, EtOH \rightarrow Removal of adsorbed gases such as N_2 , O_2 , H_2O , CO, CO_2 , ...



- Reached T on sample: $650^{\circ}C \rightarrow$ on sensor $466^{\circ}C$, $250^{\circ}C \rightarrow 145^{\circ}C$ on sensor
- Heating time: various, min. 20 min but max. 60 min
- Vacuum in good 10⁻⁸mbar



thermal heat treatment



- Applying stepwise current to the halogen lamp \rightarrow observe vacuum
- Wait till vacuum stabilizes/ lamp released adsorbed gases
- When 145°C on sensor is reached → means 250°C on sample in real
- Hold 250°C on sample for 20 min then turn off
- Wait till vacuum and cathode temperatur is back in normal range



main Cs activation



GaN Photocathode – Highlights 2020

GaN on sapphire





Fig. 2: QE tracking from GaN on sapphire



Fig. 3: SEM image of used GaN on sapphire sample

GaN on sapphire is heated at 650°C for 25 min

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- 4a and 4b showing enormous increase
- 4b activation was stopped after 55 min
- Activations 4c and 4d behaved normally (curve runs in maximum)
- ٠ 4a activation leads to 4.7% QE
- Degradation still going on fast (after 2 days only 0.5 % QE)

Fig. 1: photocurrent activation curves for GaN on sapphire

GaN on silicon







Fig. 6: SEM image of used GaN on silicon

- · GaN on silicon is heated at 250°C (20-60 min)
- All 5 cycles show same QE (about 2.6 % QE)
- Thermal treatment time seems to have no effect on QE
- Degradation for all curves ٠ similar, sample survive now about 6 days and still have 0.5 % QE left

Fig. 4: photocurrent activation curves for GaN on silicon

Fig. 5: QE tracking from GaN on silicon

12 Nov 2020



latest activation(s)

activations on GaN/sapphire #2021.01



• Thermal heat treatment: <u>250°C</u> for various times





latest activation(s)

•

GaN on Cu (Siegen)

Thermal heating: ~250°C for 20 min







GaN on Cu (Siegen)



GaN:sapphire 250°C 12 QE 11 10 9 8 7 · QE [%] GaN:Si lifetime GaN:sapphire 650°C 6 650°C ٠ 5 • GaN:Si 4 250°C 3 dirty 2 1 0 1a 1b 1c 1d 2a 2b 2c 2d 3a 3b 3c 4a 4b 4c 4d 5a 6a 6b 6c 6d 6e 7a 7b 7c 7d cycle No.

Thermal heat treatment is important for QE and lifetime

Summary

- Vacuum conditions & LED shutter improve
- Highest QE so far : 11.5%
- QE from Siegen: works but maybe the surface is still



Outlook

XPS facility in front of GaN chamber



GaN on sapphire

GaN on Si



GaN on sapphire and Si sputtered with gold

- Charaterization and comparison of commercial available GaN wafer
 → GaN on sapphire, Si, SiC (different substrates)
 - \rightarrow AFM, XPS, EDX, SEM, RBS
- Connection from activation chamber to XPS chamber \rightarrow planned in 1st quarter 2021 \rightarrow delayed
- Activation of GaN wafer with Cs and characterization of activated GaN

ightarrow further activations and improvement

- Nagoya activation: Cs and O alternatively
- Comparision to GaAs & selfmade GaN (Uni Siegen)
- Improvements on Chamber:
 - \rightarrow install heating option for anode
 - \rightarrow better temperature measurement (new IR sensor)